

WEST Search History

DATE: Saturday, June 15, 2002

<u>Set Name</u>	<u>Query</u>	<u>Hit Count</u>	<u>Set Name</u>
side by side			result set
	<i>DB=JPAB,EPAB,DWPI,TDBD; PLUR=YES; OP=ADJ</i>		
L53	(puls\$3 near6 bias near8 frequency) same (kHz) same (Ghz or Mhz)	1	L53
	<i>DB=USPT,PGPB; PLUR=YES; OP=ADJ</i>		
L52	L51 not L50	6	L52
L51	(puls\$3 near6 bias near8 frequency) same (kHz) same (Ghz or Mhz)	12	L51
L50	(puls\$3 near6 bias near8 frequency) with (kHz) with (Ghz or Mhz)	6	L50
L49	(puls\$3 near3 bias near3 frequency) with (kHz)	29	L49
L48	(puls\$3 near3 bias near3 frequency) same (kHz and Mhz)	3	L48
L47	(puls\$3 near3 bias near3 frequency) with (kHz and Mhz)	0	L47
L46	6258287.pn.	1	L46
L45	L1 and (puls\$3 near3 bias near3 frequency)	10	L45
L44	((Ar or argon) near3 (ion or plasma or sputter\$3) near3 clean\$3) same ((substrate or turbine or airfoil or blade or base) near3 temperature)	34	L44
	<i>DB=JPAB,EPAB,DWPI,TDBD; PLUR=YES; OP=ADJ</i>		
L43	((Ar or argon) near3 (ion or plasma or sputter\$3) near3 clean\$3) same ((substrate or turbine or airfoil or blade or base) near3 temperature)	8	L43
	<i>DB=USPT,PGPB; PLUR=YES; OP=ADJ</i>		
L42	L41 same (900 or 1000 or 1100 or 1200 or 1300 or 1400 or 1500)	64	L42
L41	((((plasma or ion or sputter\$3) with (clean\$3)) same (((turbine or airfoil or blade or substrate or base) near4 temperature)))	485	L41
L40	L1 and (((plasma or ion or sputter\$3) with (clean\$3)) same (((turbine or airfoil or blade or substrate or base) with temperature)))	99	L40
L39	L1 and (((plasma or ion or sputter\$3) with (clean\$3 or etch\$3)) same (((turbine or airfoil or blade or substrate or base) with temperature)))	321	L39
L38	L1 and (turbine or airfoil) and ((plasma or ion or sputter\$3) with (clean\$3 or etch\$3)) and ((turbine or airfoil or blade or substrate or base) with temperature)	30	L38
L37	L1 and (turbine or airfoil) and ((plasma or ion or sputter\$3) with (clean\$3 or etch\$3)) and ((clean\$3 or etch\$3) same (H2 or "H.sub.2" or hydrogen))	9	L37
	<i>DB=JPAB,EPAB,DWPI,TDBD; PLUR=YES; OP=ADJ</i>		
L36	1447754	3	L36
	<i>DB=USPT,PGPB; PLUR=YES; OP=ADJ</i>		
L35	L32 and ((control\$5 or regulat\$3) with (\$3flow) with (electron))	12	L35
L34	L32 and (bias near6 switch\$3)	3	L34
L33	L32 and ((puls\$3 near3 bias) same (clean\$3))	0	L33

L32	((plasma or ion or sputter\$3) with (clean\$3 or etch\$3)) and ((e-beam or (e beam) or (electron near2 (beam or cloud))) with (heat\$3 or contact\$3 or onto or direct\$3) with (substrate or base or airfoil or turbine))	609	L32
L31	(L1 or ((plasma or ion or sputter\$3) with (clean\$3 or etch\$3))) and ((puls\$3 near5 bias) same (clean\$3 or switch\$3))	47	L31
<i>DB=JPAB,EPAB,DWPI,TDBD; PLUR=YES; OP=ADJ</i>			
L30	(L1 or ((plasma or ion or sputter\$3) with (clean\$3 or etch\$3))) and (puls\$3 near5 bias)	36	L30
<i>DB=USPT,PGPB; PLUR=YES; OP=ADJ</i>			
L29	(L1 or ((plasma or ion or sputter\$3) with (clean\$3 or etch\$3))) and (puls\$3 near5 bias)	274	L29
L28	(puls\$3 near3 bias) with (switch\$3) with (ground\$3 or potential or float\$3)	26	L28
L27	L26 and (L1 or ((plasma or ion or sputter\$3) with (clean\$3 or etch\$3)))	67	L27
L26	(control\$5 or regulat\$3) with (\$3flow) with (electron) with (base or turbine or airfoil or substrate)	196	L26
<i>DB=JPAB,EPAB,DWPI,TDBD; PLUR=YES; OP=ADJ</i>			
L25	((plasma or ion or sputter\$3) with (clean\$3 or etch\$3)) and ((switch\$3 or alternat\$6) near5 (between\$2) with (clean\$3) with (heat\$3))	0	L25
<i>DB=USPT,PGPB; PLUR=YES; OP=ADJ</i>			
L24	L1 and ((switch\$3 or alternat\$6) near5 (between\$2) with (clean\$3) with (heat\$3))	2	L24
L23	L21 and (switch\$3 with ground\$3 with bias)	7	L23
L22	L21 and ((switch\$3 or alternat\$4) near6 (bias or electron))	89	L22
L21	L1 and ((plasma or ion or sputter\$3) with (clean\$3 or etch\$3))	2724	L21
<i>DB=JPAB,EPAB,DWPI,TDBD; PLUR=YES; OP=ADJ</i>			
L20	L19 and ((plasma or ion or sputter\$3) with (clean\$3 or etch\$3))	54	L20
L19	((switch\$3 or alternat\$4) near6 (bias or electron))	9184	L19
<i>DB=USPT,PGPB; PLUR=YES; OP=ADJ</i>			
L18	L17 and (bias)	28	L18
L17	((plasma or ion or sputter\$3) with (clean\$3 or etch\$3)) and (e-beam or (e beam) or (electron near2 (beam or cloud))) and (turbine or airfoil)	110	L17
L16	L14 not L15	202	L16
L15	L14 and ((plasma or ion or sputter\$3) with (clean\$3 or etch\$3)) and (e-beam or (e beam) or (electron near2 (beam or cloud)))	17	L15
L14	L1 and ((period\$7 or alternat\$6 or switch\$5) with (float\$3 or open\$3) with (clos\$4 or ground\$3))	219	L14
L13	L1 and ((switch\$3 or alternat\$4) near6 (bias or electron))	146	L13
<i>DB=JPAB,EPAB,DWPI,TDBD; PLUR=YES; OP=ADJ</i>			
L12	L1 and ((switch\$3 or alternat\$4) near6 (bias or electron))	0	L12

L11	L8 and ((etch\$3 or clean\$3) with (deposit\$3 or coat\$3 or \$4VD) with (reactor or vessel or chamber or apparatus or device))	57	L11
L10	L8 and ((etch\$3 or clean\$3) same (deposit\$3 or coat\$3 or \$4VD) same (reactor or vessel or chamber or apparatus or device))	194	L10
L9	L8 and (turbine or airfoil or engine)	4	L9
L8	((plasma or ion or sputter\$3) with (clean\$3 or etch\$3)) and (e-beam or (e beam) or (electron near2 (beam or cloud)))	1408	L8
<i>DB=USPT,PGPB; PLUR=YES; OP=ADJ</i>			
L7	L1 and (turbine or airfoil) and ((etch\$3 or clean\$3) with (deposit\$3 or coat\$3 or \$3VD) with (reactor or vessel or chamber or apparatus or device))	20	L7
L6	L5 not L4	73	L6
L5	((plasma or ion or sputter\$3) with (clean\$3 or etch\$3)) and (e-beam or (e beam) or (electron near2 (beam or cloud))) and ((etch\$3 or clean\$3) with (deposit\$3 or coat\$3 or \$3VD) with (same\$2) with (reactor or vessel or chamber or apparatus or device))	86	L5
L4	L2 and ((etch\$3 or clean\$3) with (deposit\$3 or coat\$3 or \$3VD) with (same\$2) with (reactor or vessel or chamber or apparatus or device))	13	L4
L3	L2 and (turbine or airfoil)	19	L3
L2	L1 and ((plasma or ion or sputter\$3) with (clean\$3 or etch\$3)) and (e-beam or (e beam) or (electron near2 (beam or cloud)))	459	L2
L1	((427/532).icls. or (427/533).icls. or (427/534).icls. or (427/535).icls. or (427/551).icls. or (427/566).icls. or (427/585).icls. or (427/595).icls. or (427/596).icls. or (427/248.1).icls. or (427/444).icls. or (204/192.1).icls. or (204/192.32).icls. or (118/715).icls. or (118/723R).icls. or (118/723EB).icls. or (118/723FE).icls. or (118/725).icls. or (118/728).icls. or (118/729).icls. or (118/730).icls. or (118/72).icls. or (216/37).icls. or (216/63).icls. or (216/66).icls. or ((216/67)!ICLS.))	7278	L1

END OF SEARCH HISTORY



WEST Search History

DATE: Friday, June 14, 2002

Set Name Query

side by side

Hit Count Set Name

result set

DB=USPT,PGPB; PLUR=YES; OP=ADJ

L10	((substrate or turbine or blade or base) with (periodically) with (ground\$3 or reference or potential) with (switch\$3))	53	L10
L9	L8 and ((electron beam) or (e beam))	3	L9
L8	((substrate or turbine or blade or base) with (periodically) with ground\$3)	110	L8
L7	L4 and ((substrate or turbine or blade or base) with (ground\$3) with (Hz or kHz or MHz or frequency or switch\$3))	12	L7
L6	L4 and ((substrate or turbine or blade or base) with (ground\$3))	148	L6
L5	L4 and ((substrate or turbine or blade or base) with (periodically) with ground\$3)	0	L5
L4	L3 and ((clean\$3 or heat\$3 or preclean\$3) same ((electron beam) or (e beam)))	2741	L4
L3	(427/\$).icls. or (204/\$).icls. or ((118/\$).icls.)	90579	L3

DB=JPAB,EPAB,DWPI,TDBD; PLUR=YES; OP=ADJ

L2	(Dopper and ((electron beam) same (clean\$3 or coat\$3)))	1	L2
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DB=USPT,PGPB; PLUR=YES; OP=ADJ

L1	(Dopper.in. and ((electron beam) same (clean\$3 or coat\$3)))	3	L1
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END OF SEARCH HISTORY